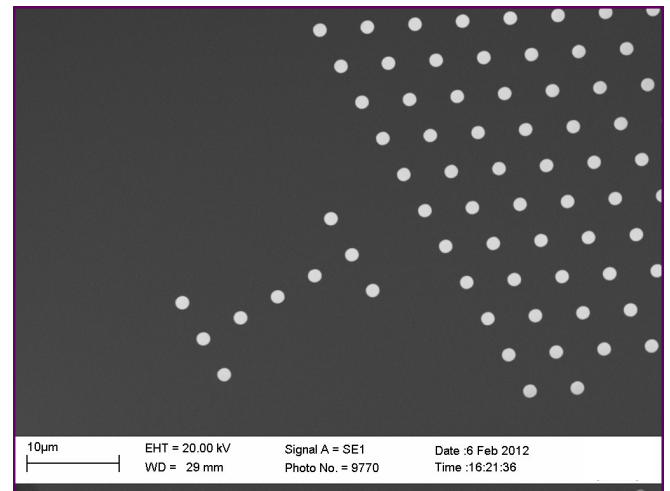
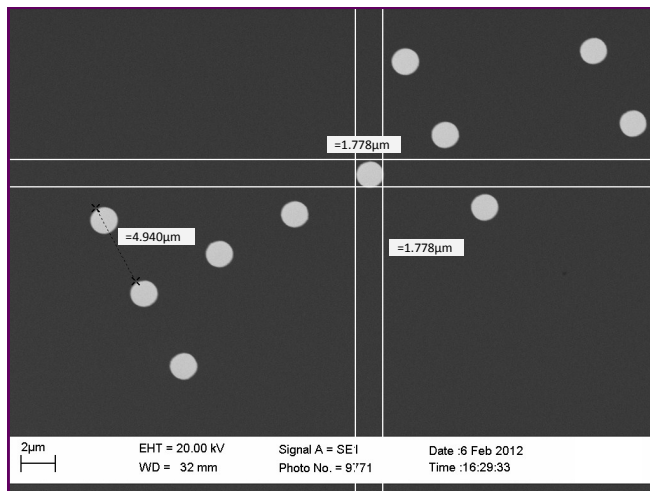


NORCADA MICROPOROUS LOCATION-TAGGED TEM DEVICES

Features

- 1.8 μm Holes 5 μm pitch
- Silicon Nitride film with microporous pattern and tagged locations
- The film is mechanically robust and is fabricated in 50nm thicknesses
- These devices can be used in high beam intensity TEM
- Part Number: NH050A2

NANOTECHNOLOGY & MICROSCOPY



Applications

The advantage of these membranes is that the films will provide a supportive platform for overhanging samples that lay across the micropores.

A string-shaped material can be placed or grown overhanging across the holes. This allows for having no thin film background for the microscopy image.

These membranes have many applications in high resolution TEM, STEM and STXM.

